



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

6/A  
B/A  
7-24-01

In re application of:

Shuzo Fujimura et al.

Application No.: 09/328,939

Filed: June 9, 1999

For: SURFACE TREATMENT  
METHOD AND EQUIPMENT

Examiner: Shamim Ahmed

Art Unit: 1746

AMENDMENT

RECEIVED  
JUL 23 2001  
TC 1700

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action mailed March 12, 2001, please amend the above-identified application as follows, where the period to respond has been extended by way of the attached petition:

IN THE SPECIFICATION:

At page 4 of the specification, please cancel the following language:

"Figs. 2-6 are process diagrams according to embodiments of the present invention; and

Figs. 7 and 8 are plasma treatment tools according to embodiments of the present invention."

Insert the following language in their place:

--Fig. 2 is a simplified diagram of a concentraton plotted against flow rate according to an embodiment of the present invention;

Fig. 3 is a simplified diagram of a concentraton plotted against flow rate according to an alternative embodiment of the present invention;

Fig. 4 is a simplified diagram of a concentraton plotted against flow rate according to an alternative embodiment of the present invention;

Fig. 5 is a simplified diagram of a concentraton plotted against flow rate according to an alternative embodiment of the present invention;

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